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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Kay Ming Lee, Cheng-Wen Fan, Jiunn-Ren
5 Hwang, Chih-Chiang Liu
Examiner: MOHAMEDULLA, SALEHA R
Filing Date: 05/12/2002 Art Unit: 1756
App. No.: 10/063,779 Docket No.: NAUP0469USA

10 Title: METHOD OF CORRECTING A MASK LAYOUT

To: Commissioner for Patents
P.O. BOX 1450
Alexandria, VA 22313-1450

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Subject: Response to the Office action dated 03/19/2004

Dear Sir:

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INTRODUCTORY COMMENTS

In response to the Office action identified above,
the above-identified application is to be amended as
indicated in the following section. Consideration of
25 all amendments is politely requested.